

EE143 Lab Week 7 Measurement Checklist:
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1) Preliminary Measurements:

Furnace Temperature:	
Control Wafer Sheet Resistance:	

2) Pre-Deposition:

Time (sec)	
Sheet Resistance	

SOG Etch Time:

Drive-In

Time (sec)	
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Anneal:

Time (sec)	
Sheet Resistance	

3) Measurements after Process Completion:
Intermediate Oxide Thickness (Nanospec):

Questions (In preparation for Lab Report 1):

Calculate Theoretical Oxide Thickness using Deal-Grove Model

Calculate surface dopant concentration from the sheet resistance after pre-deposition and drive-in.